Data Sheet- EddyCus® TF map 2525 Series

P_T_2525_12

Highlights

- Contact-free imaging
- High resolution imaging (25 to 1,000,000 points)
- Defect imaging
- Mapping of encapsulated layers

Parameters

- Sheet resistance (Ohm/sq)
- Metal layer thickness (nm, µm)
- Metal substrate thickness (µm)
- Anisotropy
- Defects
- Integrity assessment

Applications

- Architectural glass (LowE)
- Touch screens and flat monitors
- OLED and LED applications
- Smart-glass applications
- Transparent antistatic foils
- Photovoltaics
- Semiconductors
- De-icing and heating applications
- Batteries and fuel cells
- Packaging materials

Materials

- Metal films and meshes
- Conductive oxides
- Nanowire films
- Graphene, CNT, Graphite
- Printed films
- Conductive polymers (PEDOT:PSS)
- Other conductive films and materials

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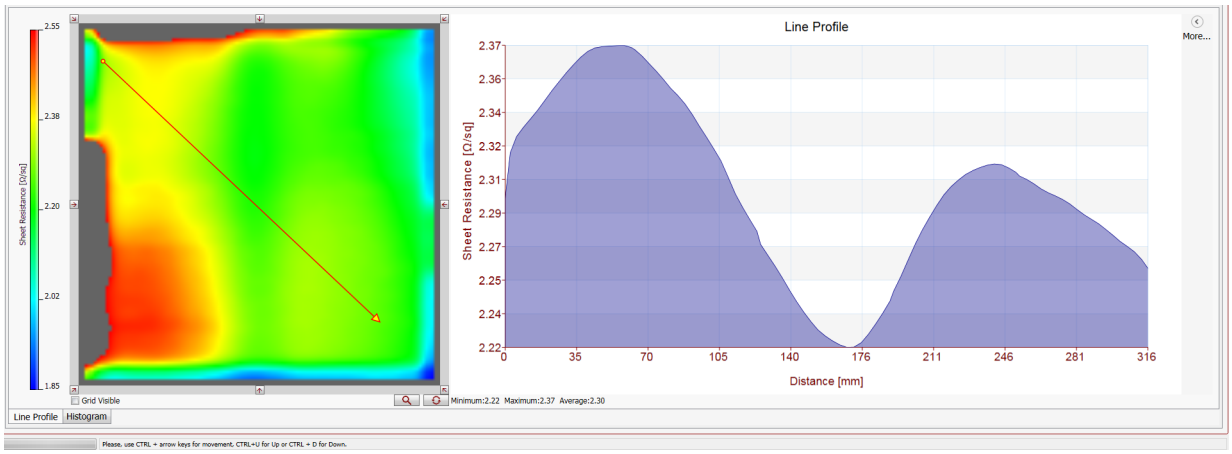
Made and Engineered in Germany

Innovation Award by Free State of Saxony 2013
1st Place

EddyCus® TF map 2525 Series

Measurement technology	Non-contact eddy current sensor
Substrates	E.g. Foils, glass, wafer, etc.
Max. Scanning area	10 inch / 254 x 254 mm (larger on request)
Edge effect correction / exclusion	2 mm edge exclusion for standard sizes
Max. Sample thickness / sensor gap	2 / 5 / 10 / 25 mm (defined by the thickest sample)
Sheet resistance range accuracy can be optimized over sheet resistance decade within a customer specified range	Low 0.0001 - 10 Ohm / sq; 2 to 8 % accuracy Standard 1 - 1,000 Ohm / sq; 2 to 8 % accuracy High 10 - 10,000 Ohm / sq; 4 to 8 % accuracy
Thickness measurement of metal films (e.g. Aluminum, Copper)	2 nm - 2 mm (in accordance with sheet resistance)
Scanning Pitch	1 / 2 / 5 / 10 mm (other on request)
Measurement points per time (quadratic shape)	10,000 measurement points in 5 minutes 1,000,000 measurement points in 30 minutes
Scanning time	4 inch / 100 x 100 mm in 0.5 to 5 minutes (1-10mm pitch) 8 inch / 200 x 200 mm in 1.5 to 15 minutes (1-10mm pitch)
Device dimension (w/h /d) / weight	23.6 x 9.05 x 31.5 inch / 549 x 236 x 786(836) mm / 27 kg
Available features	Metal thickness imaging Anisotropy sheet resistance sensor

Software and Handling - Sheet Resistance Analayzer 2.0